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Dated: March 2006 Signature: James P. Zeller

Docket No.: 29926/39496  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Re Patent Application of:  
Hyug-Jin Kwon

Application No.: 10/615,062

Confirmation No.: 8080

Filed: July 8, 2003

Art Unit: 1763

For: BATCH TYPE ATOMIC LAYER  
DEPOSITION APPARATUS AND IN-SITU  
CLEANING METHOD THEREOF

Examiner: S. MacArthur

**RESPONSE TO OFFICIAL ACTION**

MS Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the official action dated December 30, 2005, for the above-identified U.S. patent application, please consider the following **Remarks**, which begin on page 2 of this paper.